

InSb Nanoflags: Growth and Transport Study

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Introduction and Motivation

InSb, owing to its low electron effective mass, high electron mobility, small bandgap and strong spin-orbit interaction, appears to be a promising material to investigate emerging exotic bound states at superconductor/semiconductor interfaces.

• Nanoflag (NF) geometry simplifies the device fabrication process and enables to work with more advanced device geometries with respect to nanowires.

•Therefore, it is important to understand the growth mechanism so as to have a better control of morphology and quality.

InSb nanosails (twin induced)^[1] and InSb nanosheets (Ag-assisted)^[2] have been already grown by employing MBE and MOVPE. We have synthesized InSb

Experimental Details

•Au-assisted Chemical Beam Epitaxy (CBE). •MO precursors: Trimethylindium (TMIn), Tertiarybutylarsine (TBAs) and Trimethylantimony (TMSb)

• Substrates: InAs(111)B

• Catalyst: 30 nm Au colloids (Density \approx 5 per μ m²) deposited on the substrate at RT. •InSb growth temperature (ΔT) is referenced to InAs growth temperature (T_{InAs}) .



Riber C-21 CBE

nanoflags (NFs) by Au-assisted Chemical Beam Epitaxy (CBE) for the first time.

(1) **Rotating substrate**



□ Rotation of the substrate is a crucial parameter because it imparts symmetry or asymmetry which is necessary for the growth of InSb NF.

Thickness

(2) Temperature of InSb (ΔT)



 $\Delta T = -20^{\circ}$



 $\Delta T = -10^{\circ}$

Growth rates for **length**, width and thickness linearly decreases with increasing in ΔT . \Box For InSb NF, $\Delta T = -20^{\circ}$ is the optimized temperature.

(3) Increasing Sb flux



(5) Transport Measurements

□ To assess the electronic quality of InSb NF, preliminary electrical measurements are performed in Hall bar configuration at low temperature



- □ The sample is grown by adding an additional step of increasing Sb flux from 2.3 torr to 2.6 torr while keeping the In flux constant at 0.6 torr at $\Delta T = -20^{\circ}$ with non rotating substrate.
- The cool down protocol is done in absence of group V flux to avoid growth at sidewalls of NWs.

(4) Growth time



(T = 4.2 K).

- □ For the device fabrication, the as-grown InSb NF are first mechanically transferred to a SiO_2/Si^{++} substrate.
- □ In a four-probe measurement, by sweeping the back gate (BG) voltage, we can modulate the carrier density in the NF channel – from a region of low conductance / high resistance, i.e. depletion region, to a region of high conductance / low resistance, i.e. accumulation region. These measurements show that the sample is intrinsically n-type doped and that we are in electron transport regime.



$$\mathbf{u}_{FE} = \frac{\mathbf{L}}{\mathbf{W}\mathbf{C}_{ox}} \left(\frac{\mathbf{d}\mathbf{G}}{\mathbf{d}\mathbf{V}_{BG}}\right) \qquad C_{ox} \text{ (300nm SiO}_2\text{)= 11.6 nF/cm}^2 \text{ ; } \frac{L}{W}\text{= 1 ; } \frac{\mathbf{d}\mathbf{G}}{\mathbf{d}\mathbf{V}_{BG}}\text{= 6.89 x 10}^{-6} \frac{A}{V^2}$$
$$\mu_{FE} = 594 \text{ cm}^2/\text{Vs}$$

 \Box From a Hall measurement, the carrier concentration is found to be 3×10^{16} cm⁻³ at V_{BG} = 11 V. □ The two-probe I-V curves shows modulation for positive BG.





SEM image of InSb NF Hall bar device